

**INVENTOR'S DECLARATION FOR  
PATENT APPLICATION**

As below named inventors, we hereby declare that:

Our residence, post office address and citizenship are as stated below next to our names;

We believe we are the original, first and sole joint inventors of the subject matter which is claimed and for which a patent is sought on the invention entitled

**RF COIL DESIGN FOR IMPROVED FILM UNIFORMITY  
OF AN ION METAL PLASMA SOURCE**

the specification of which: (check one)

  X   is attached hereto.

       was filed on  
under Attorney's Docket Number  
as Application Serial No.  
and was amended on \_\_\_\_\_ (if applicable).

We hereby state that we have reviewed and understand the contents of the above identified specification, including the claims, as amended by any amendment referred to above.

We acknowledge the duty to disclose information which is material to the patentability of this application in accordance with 37 CFR 1.56, including for continuation-in-part applications, material information which became available between the filing date of the prior application and the national or PCT international filing date of the continuation-in-part application.

We hereby declare that all statements made herein of our own knowledge are true and that all statements made on information and belief are believed to be true; and further that these statements were made with the knowledge that willful false statements and the like so made are punishable by fine or imprisonment, or both, under 18 U.S.C 1001 and that such willful false statements may jeopardize the validity of the application or any patent issued thereon.

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FULL NAME OF INVENTOR: Jui-Mu Cho

INVENTOR'S SIGNATURE: Jui-Mu Cho DATED: 9/10/2003

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FULL NAME OF INVENTOR: Wen-Cheng Yang

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INVENTOR'S SIGNATURE: Wen Jung Yang DATED: 9/10/2003

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FULL NAME OF INVENTOR: Tay-Lang Huang

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FULL NAME OF INVENTOR: Te-Hung Hsieh

INVENTOR'S SIGNATURE: Te-Hung Hsieh DATED: 9/18/2003

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Citizenship: ✓ R.O.C

POST OFFICE ADDRESS: same as residence

Citizenship: ✓ R.O.C

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:	§	Attorney Docket No.:	24061.30
Cho et al.	§		TSMC2002-0969
	§		
Serial No.: Unknown	§	Customer No.	27683
	§		
Filed: Herewith	§	Group Art Unit:	Unknown
	§		
For: RF ANTENNA DESIGN FOR	§	Examiner:	Unknown
IMPROVED FILM UNIFORMITY	§		
OF AN ION METAL PLASMA	§		
SOURCE	§		

Commissioner for Patents  
Washington, D.C. 20231

POWER OF ATTORNEY FOR PATENT APPLICATION

As a representative of the Assignee, Taiwan Semiconductor Manufacturing, Inc., I hereby appoint the following attorneys and/or agents to prosecute this application and transact all business in the Patent and Trademark Office connected therewith.

David M. O'Dell (Reg. No. 42,044); David L. McCombs (Reg. No. 32,271); Jeffrey M. Becker (Reg. No. 35,442); James R. Bell (Reg. No. 26,528); Timothy F. Bliss (Reg. No. 50,925); Randall C. Brown (Reg. No. 31,213); Randall E. Colson (Reg. No. 40,566); Michael A. Davis, Jr. (Reg. No. 35,488); Ruben C. DeLeon (Reg. No. 37,812); Andrew S. Ehmke (Reg. No. 50,271); Rita M. Irani (Reg. No. 31,028); Warren B. Kice (Reg. No. 22,732); J. Andrew Lowes (Reg. No. 40,706); Todd Mattingly (Reg. No. 40,298); John Montgomery (Reg. No. 31,124); Bill R. Naifeh (Reg. No. 44,962); Gloria Norberg (Reg. No. 36,706); and Chien Wei Chou (Reg. No. 41,672).

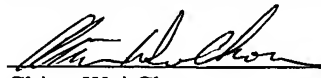
Please address all correspondence and telephone calls regarding this application to:

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The undersigned is the representative for the Assignee of the entire right, title, and interest in the patent application identified above. A copy of the assignment or other documents in the chain of title are attached.

The undersigned (whose title is supplied below) is authorized to act on behalf of the Assignee.

Taiwan Semiconductor Manufacturing, Inc.



Chien-Wei Chou  
Title: Director, IP Division

\_\_\_\_\_  
Date